



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: W. SCHWARZENBACH et al. Confirmation No.: 9739

Application No.: 10/733,729 Group Art Unit: 2818

Filing Date: December 12, 2003 Examiner: David Nhu

For: METHOD OF MAKING CAVITIES  
IN A SEMICONDUCTOR WAFER Attorney Docket No.: 4717-9200

**LETTER CORRECTING PRIORITY CLAIM**

**Mail Stop Issue Fee**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicants submit the following correction of their priority claim.

Remarks begin on page 2 of this paper.

No fees are believed to be due for the filing of this Amendment. Please charge any required fees to Winston & Strawn LLP Deposit Account No. 50-1814.